

IN THE CLAIMS:

Please cancel claims 1-12 without prejudice or disclaimer, and substitute new claims 13-28 therefor as follows:

Claims 1-12 (Canceled)

13. (New) A method for manufacturing a mold tool adapted to be used for forming a structured nano scale pattern on an object and having a layer, which is anti-adhesive with regard to the object, said method comprising the following steps:

providing a stamp blank with a structured pattern on a surface,

depositing a layer of a metal on the patterned surface, said metal having a stable oxidation number and being capable of forming a mechanically stable oxide film,

oxidising the layer of metal to form an oxide film, and

applying at least one reagent on the oxide film, said reagent comprising molecule chains, each having a linkage group, which is chemically bonded with the oxide film, wherein the molecule chains either from the beginning comprise at least one group comprising fluorine, or are provided with at least one such group in a subsequent treatment.

14. (New) The method of claim 13 wherein said linkage group is chemically bonded by a covalent bond with said oxide film.

15. (New) The method according to claim 13, wherein said metal is chosen from titanium, zirconium, niobium, tantalum and aluminium, and mixtures thereof.

16. (New) The method according to claim 13, wherein said linkage group is chosen among silane groups, phosphate groups and carboxylic groups.

17. (New) The method according to above claim 13, wherein the metal is furnished to the pattern equipped surface in an evaporated form.

18. (New) The method according to above claim 13, wherein the layer of metal is oxidised by bringing it in contact with a gas comprising oxygen, such as surrounding air, filtered surrounding air, or a synthetical gas mixture comprising oxygen.

19. (New) The method according to claim 13, wherein the patterned surface is coated with a layer of metal with a thickness (HT) of 1-300 nm.

20. (New) The method according to any one of claims 13-17, wherein the patterned surface is coated with a layer of metal with a thickness (HT) of 1-100 nm.

21. (New) A mold tool adapted to be used for forming a structured nano scale pattern on an object and having a layer, which is anti-adhesive with regard to the object, said mold tool comprising a stamp blank, having a structured pattern on its surface, and a layer of a metal, having a stable oxidation number and being capable of forming a mechanically stable oxide film, which layer of metal has been applied on said surface and thereafter brought to oxidise to form a mechanically stable oxide film, wherein the anti-adhesive layer comprises molecule chains, each having at least one linkage group, which by chemical bonding are bonded with the oxide film, and at least one group comprising fluorine.

22. (New) The mold tool according to claim 21 wherein said at least one linkage group is chemically bonded by a covalent bond with said oxide film.

23. (New) The mold tool according to claim 21, wherein said layer of metal has a thickness (HT) of 1-300 nm.

24. (New) The mold tool according to claim 21, wherein said layer of metal has a thickness (HT) of 1-100 nm.

25. (New) The mold tool according to claim 21, wherein said stamp blank comprises a metal and/or silicon.

26. (New) The mold tool according to claim 25, wherein said stamp blank is a nicellic stamp blank.

27. (New) The mold tool according to claim 21, wherein said layer of metal is an aluminium, zirconium, tantalum, niobium or titanium layer.

28. (New) A storage medium, such as a CD or DVD or a hard disc, wherein a mold tool according to any one of claims 21-23 has been used for forming a structured pattern on the medium.